

Day : Monday
Date: 5/17/2004

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PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = HUANG

First Name = JUDY

Application#	Patent#	Status	Date Filed	Title	Inventor Name 46
60218407	Not Issued	159	07/14/2000	METHOD AND APPARATUS FOR TREATING LOW K DIELECTRIC LAYERS TO REDUCE DIFFUSION	HUANG, JUDY H.
10684079	Not Issued	030 2825	10/09/2003 438/1101	SILICON CARBIDE DEPOSITION FOR USE AS A LOW DIELECTRIC CONSTANT ANTI-REFLECTIVE COATING	HUANG, JUDY JFW
10655438	Not Issued	030	09/04/2003	PLASMA TREATMENT FOR COPPER OXIDE REDUCTION	HUANG, JUDY H.
10252195	6734102	150	09/23/2002	PLASMA TREATMENT FOR COPPER OXIDE REDUCTION	HUANG, JUDY
10184681	Not Issued	093	06/28/2002	HERMETIC SILICON CARBIDE	HUANG, JUDY HSIU-CHIH
10137209	Not Issued	071 1711	04/30/2002 429/387	BINDER-ENRICHED SILICALITE ADHESION LAYER AND APPARATUS FOR FABRICATING THE SAME	HUANG, JUDY JFW
10060685	Not Issued	060	01/29/2002	SYSTEM AND METHOD FOR COATING SUBSTRATES USING INK JET TECHNOLOGY	HUANG, JUDY
10013182	6700202	150	12/07/2001	SEMICONDUCTOR DEVICE HAVING REDUCED OXIDATION INTERFACE	HUANG, JUDY H.
10011369	6669858	150	11/05/2001	INTERGRATED LOW K DIELECTRICS AND ETCH STOPS	HUANG, JUDY H.
10011368	Not Issued	093	11/05/2001	INTEGRATED LOW K DIELECTRICS AND ETCH STOPS	HUANG, JUDY H. JFW
09975193	Not Issued	161	10/10/2001	PHOTOACTIVE SACRIFICIAL POROGENS IN POROUS DIELECTRIC FORMATION:	HUANG, JUDY

				FREE-RADICAL PATHWAYS	
09954399	Not Issued	168	09/10/2001	PHOTOACTIVE SACRIFICIAL POROGENS IN POROUS DIELECTRIC FORMATION: FREE-RADICAL PATHWAYS	HUANG, JUDY
09953547	Not Issued	061 177	09/14/2001 4/28/34	INTERPARTICLE BINDERS FOR PRODUCING LOW DIELECTRIC CONSTANT MATERIALS	HUANG, JUDY JFW
09902518	Not Issued	094 2824	07/10/2001 4/28/798	METHOD AND APPARATUS FOR TREATING LOW K DIELECTRIC LAYERS TO REDUCE DIFFUSION	HUANG, JUDY H. JFW
09823721	6436843	150	03/30/2001	SYSTEM AND METHOD FOR COATING SUBSTRATES USING INK JET TECHNOLOGY	HUANG, JUDY
09782985	6533855	150	02/13/2001	DISPERSIONS OF SILICALITE AND ZEOLITE NANOPARTICLES IN NONPOLAR SOLVENTS	HUANG, JUDY
09632502	6517913	150	08/03/2000	METHOD AND APPARATUS FOR REDUCING PERFLUOROCOMPOUND GASES FROM SUBSTRATE PROCESSING EQUIPMENT EMISSIONS	HUANG, JUDY H.
09587355	Not Issued	161	06/05/2000	SILICON NITRIDE ANTI-REFLECTIVE COATING FOR 193 NM LITHOGRAPHY	HUANG, JUDY H.
09585258	6358573	150	06/02/2000	MIXED FREQUENCY CVD PROCESS	HUANG, JUDY
09573499	6324439	150	05/16/2000	METHOD AND APPARATUS FOR APPLYING FILMS USING REDUCED DEPOSITION RATES	HUANG, JUDY H.
09551021	6209484	150	04/17/2000 ?	METHOD AND APPARATUS FOR DEPOSITING AN ETCH STOP LAYER	HUANG, JUDY H.
09550449	Not Issued	161	04/17/2000	METHOD AND APPARATUS FOR DEPOSITING AN ETCH STOP LAYER	HUANG, JUDY H.
09550151	6395092	150	04/17/2000	PROCESS FOR DEPOSITING HIGH DEPOSITION RATE HALOGEN-DOPED SILICON OXIDE LAYER	HUANG, JUDY
09457086	6541369	150	12/07/1999	METHOD AND APPARATUS FOR REDUCING FIXED CHARGES IN A	HUANG, JUDY

				SEMICONDUCTOR DEVICE	
09418818	Not Issued <i>appeal</i>	121 <i>1763</i>	10/15/1999	METHOD AND APPARATUS FOR DEPOSITING ANTIREFLECTIVE COATING	HUANG, JUDY H. <i>IFW</i>
09365129	6355571	150	07/30/1999	METHOD AND APPARATUS FOR REDUCING COPPER OXIDATION AND CONTAMINATION IN A SEMICONDUCTOR DEVICE	HUANG, JUDY H.
09336525	Not Issued	080	06/18/1999	PLASMA TREATMENT TO ENHANCE ADHESION AND TO MINIMIZE OXIDATION OF CARBON-CONTAINING LAYERS	HUANG, JUDY
09329012	6340435	150	06/09/1999	INTEGRATED LOW K DIELECTRICS AND ETCH STOPS	HUANG, JUDY H.
09270039	Not Issued	041 <i>2823</i>	03/16/1999 <i>438/158</i>	IN SITU DEPOSITION OF A LOW K DIELECTRIC LAYER, BARRIER LAYER, ETCH STOP, AND ANTI-REFLECTIVE COATING FOR DAMASCENE APPLICATION	HUANG, JUDY H. <i>IFW</i>
09219945	6635583	150	12/23/1998	SILICON CARBIDE DEPOSITION FOR USE AS A LOW-DIELECTRIC CONSTANT ANTI-REFLECTIVE COATING	HUANG, JUDY
09193920	Not Issued	161	11/17/1998	PLASMA TREATMENT FOR COPPER OXIDE REDUCTION	HUANG, JUDY
09165248 <i>2003 608992</i>	Not Issued <i>appeal</i>	120 <i>2823</i>	10/01/1998 <i>138/158</i>	SILICON CARBIDE DEPOSITION FOR USE AS A BARRIER LAYER AND AN ETCH STOP	HUANG, JUDY <i>IFW</i>
09113534	Not Issued	041	07/10/1998	PLASMA PROCESS TO DEPOSIT SILICON NITRIDE WITH HIGH FILM QUALITY AND LOW HYDROGEN CONTENT	HUANG, JUDY
08980520	6098568	150	12/01/1997	MIXED FREQUENCY CVD PROCESS AND APPARATUS	HUANG, JUDY
08950923	5908672	150	10/15/1997 <i>9</i> <i>1</i>	METHOD AND APPARATUS FOR DEPOSITING A PLANARIZED PASSIVATION LAYER	HUANG, JUDY H.
08923501	6451686	150	09/04/1997	CONTROL OF SEMICONDUCTOR DEVICE ISOLATION PROPERTIES THROUGH INCORPORATION OF	HUANG, JUDY

				FLUORINE IN PETEOS FILMS	
08852788	6156149	150	05/07/1997	IN SITU DEPOSITION OF A DIELECTRIC OXIDE LAYER AND ANTI-REFLECTIVE COATING	HUANG, JUDY H.
08852787	6127262	150	05/07/1997	METHOD AND APPARATUS FOR DEPOSITING AN ETCH STOP LAYER	HUANG, JUDY H.
08852786	6083852	150	05/07/1997	METHOD FOR APPLYING FILMS USING REDUCED DEPOSITION RATES	HUANG, JUDY H.
08837641	6077764	150	04/21/1997	PROCESS FOR DEPOSITING HIGH DEPOSITION RATE HALOGEN-DOPED SILICON OXIDE LAYER	HUANG, JUDY H.
08743628	6562544	150	11/04/1996	METHOD AND APPARATUS FOR IMPROVING ACCURACY IN PHOTOLITHOGRAPHIC PROCESSING OF SUBSTRATES	HUANG, JUDY H.
08741272	6187072	150	10/30/1996	METHOD AND APPARATUS FOR REDUCING PERFLUOROCOMPOUND GASES FROM SUBSTRATE PROCESSING EQUIPMENT EMISSIONS	HUANG, JUDY H.
08672888	5968324	150	06/28/1996	METHOD AND APPARATUS FOR DEPOSITING ANTIREFLECTIVE COATING	HUANG, JUDY H.
08579375	Not Issued	168	12/27/1995	METHOD AND APPARATUS FOR REDUCING PERFLUOROCOMPOUND GASES FROM SUBSTRATE PROCESSING EQUIPMENT EMISSIONS	HUANG, JUDY H.
08567338	Not Issued	161	12/05/1995	ANTI-REFLECTIVE COATING AND METHOD FOR DEPOSITING THE SAME	HUANG, JUDY H.
08550668	5792269	150	10/31/1995	GAS DISTRIBUTION FOR CVD SYSTEMS	HUANG, JUDY H.

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